



2822/15

PATENT
005586/D8326 (81784.0208)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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TECHNOLOGY CENTER 2800

In re application of:

Hidenori OGATA et al.

Serial No: 09/291,538

Filed: April 14, 1999

For: LASER ANNEAL METHOD OF A
SEMICONDUCTOR LAYER

Art Unit: 2822

Examiner: M.A. Wilczewski

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to:

Commissioner for Patents
Washington D.C. 20231, on

December 20, 2002

Date of Deposit

John P. Scherlacher, Reg. No. 23,009

Name

Signature: *John P. Scherlacher* Date: 12/20/02

#7
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(34)

PETITION FOR EXTENSION OF TIME

Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to December 25, 2002, the period for response to the Office Action dated June 25, 2002. A check for \$920 is enclosed. The responsive paper(s) are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: December 20, 2002

By:

John P. Scherlacher
John P. Scherlacher
Registration No. 23,009
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